




스핀코터 모델 [Home](#)

큰 시료용 스핀코터는 주문 제작 가능

Natural Polypropylene Models(NPP)

가격단위:원(부가세별도)

CHEMICAL/ DISPENSE	용도 VS. 모델명	DRY	RINSE	CLEAN	ETCH	MANUAL/ COATING	AUTO/ COATING	DEVELOP	DesCription IND :키보드 분리형,	시료 사 이즈	가격
MANUAL DISPENSE	SPIN150- NPP 	●	●	●		●			재질 :NPP 서보모터 Accuracy: +-1 RPM 50메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 275 (w) x 240 (d) x 450 (h) mm	~ Ø160mm (6") or 4"x4"	0
	SPIN150- NPP-IND 	●	●	●		●			키보드 분리형 글로브박스내 설치 시 유용		0
	MCD200- NPP 	●	●	●		●			재질 :NPP 서보모터 Accuracy: +-1 RPM 50메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 330 (w) x 550 (d) x 320 (h) mm		0
	MCD200- NPP-IND 	●	●	●		●			키보드 분리형 글로브박스내 설치 시 유용	~ Ø260mm (8") or 6"x6"	0
AUTO- DISPENSE	ACD200- NPP 	●	●	●			●		재질 :NPP 서보모터 Accuracy: +-1 RPM 50메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 330 (w) x 550 (d) x 320 (h) mm		0
	ACD200- NPP-IND	●	●	●			●		키보드 분리형 글로브박스내 설치 시 유용		0
MANUAL	MCD300- NPP	●	●	●		●			재질 :NPP 서보모터 Accuracy: +-1 RPM 99 메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 43cm (w) x 65cm (d)		0

AUTO-DISPENSE		●	●	●	●	●	●	●	step RPM : 1-10.000 rpm; 외형치수: 330 (w) x 550 (d) x 320 (h) mm	0
	ACD200-PTFE-IND	●	●	●	●	●	●	●	키보드 분리형 글로벌박스내 설치 시 유용	0
MANUAL DISPENSE		●	●	●	●	●	●	●	재질 :테플론 서보모터 Accuracy: +-1 RPM 99 메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 43cm (w) x 65cm (d) x 31cm	0
	MCD300-PTFE-IND	●	●	●	●	●	●	●	키보드 분리형 글로벌박스내 설치 시 유용	0
AUTO-DISPENSE		●	●	●	●	●	●	●	재질 :테플론 서보모터 Accuracy: +-1 RPM 99 메모리, 99 step RPM : 1-10.000 rpm; 외형치수: 43cm (w) x 65cm (d) x 31cm	0
	ACD300-PTFE-IND	●	●	●	●	●	●	●	키보드 분리형 글로벌박스내 설치 시 유용	0

~
Ø360mm
(12")
or 8"x8"

CHEMICAL/ DISPENSE	용도 VS. 모 텔명	DRY	RINSE	CLEAN	ETCH	MANUAL/ COATING	AUTO/ COATING	DEVELOP	DesCription	시료 사 이즈	가 격
MANUAL DISPENSE	Polos 600 SST	●	●	●		●				~ Ø550mm	

제품 특성:

- 수동형 디스펜싱기능 부터 완전 자동 디스펜싱까지 폭넓은 선택 가능한 제품군
- 무진동 설계 :최대 12,000RPM
- 설치면적 최소화 설계
- 용도에따른 주문제작 가능
- 고내화학성 하우스링및 간편한 클리닝 가능
- 글로벌 박스내에서도 작업 가능한 편리하고 큼직한 키보드 스타일
- 고신뢰성 반복작업 가능
- 복잡한 작업 가능한 하이스텝 -메모리 기능,99Step-99memory:MCD 200~
- Programmable Relays, allowing process controlled interfacing with external hardware
- German Quality

- [SPIN150 Spin Coater](#)
- [RPM verific. curve](#)
- [POLOS Hotplate](#)
- [Options](#)
- [OEM In-Deck Models Spin Coater](#)
- [MCD300-PTFE-HD Spin Coater](#)
- [MCD300-NPP-HD Spin Coater](#)
- [MCD200-PTFE-HD Spin Coater](#)
- [MCD200-NPP Spin Coater](#)
- [Chucks for Spin Processor SPIN150, MCD200 up to ACD300](#)
- [ACD300-PTFE-HD Spin Coater](#)
- [ACD300-NPP-HD Spin Coater](#)
- [ACD200-PTFE-HD Spin Coater](#)
- [ACD200-NPP Spin Coater](#)

Polos Spincoater 작동모습

- **Determination of spincoating uniformity and wafer to wafer uniformity of the APT Spincoating system using AZ5214E resist.**
(By: T. Zijlstra TUDelft B. de Lange TUDelft B. van Weelde SPS)

- APT Spincoater의 특징
Wafer uniformity의 향상을 위한 2 Point

1. acceleration during ramp up: Changing the acceleration resulted in more smooth resist films, i.e. "comet" tails disappeared when the acceleration during ramp up was increased to 1000 rpm per second, with a final spinning speed of 5000 rpm.

2. Airflow in the spinbowl: Reducing the the airflow to zero resulted in circular uniform resist pattern on the wafer

- **Wafer to wafer uniformity:**
** For these experiments we used the "optimized" conditions, i.e. a ramp up of 1000 rpm per second for five seconds, then a spinning speed of 5000 rpm for 55 seconds. The airflow in the spinning bowl was reduced to zero.

1. The spinning conditions for AZ 5214E was optimized, although we are convinced that conditions could have been further optimized if we would have had more time available.

2. The wafer uniformity found, is better than 2.5%

3. The wafer to wafer uniformity was found to be 3%.

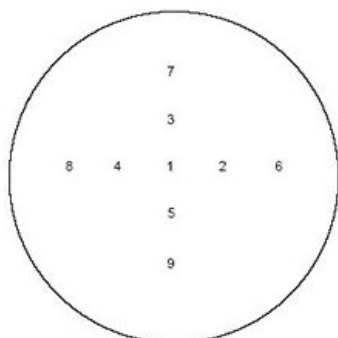
4. Improving the experimental setup would probably resulted in better wafer uniformity and wafer to wafer uniformity.

Resist thickness on different positions on a silicon wafer.

wafemr	positie 1	positie 2	positie 3	positie 4	positie 5	positie 6	positie 7	positie 8	positie 9	stdev	average	uniformity %
1	1216	1227	1200	1221	1193	1196	1179	1172	1161	22,64	1196,11	1,89
2	1061	1014	1067	1043	1061	997	1015	994	995	25,12	1035,11	2,39
3	1057	1089	1052	1061	1073	1000	1014	1000	1038	23,23	1044,22	2,18
4	1067	1104	1106	1100	1086	1055	1084	1057	1038	27,18	1083,00	2,51

wafer to wafer uniformity is about 3%.

Measurement points on a 4 inch wafer (the wafer edge of one centimeter is excluded)



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